

1763

PATENT
Atty. L. No. APPM/2981.P1/IBSS/CPS/DV

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Reimer, et al.

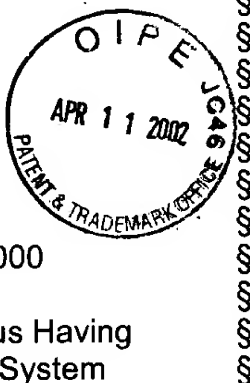
Serial No.: 09/505,580

Confirmation No.: 5947

Filed: February 16, 2000

For: Processing Apparatus Having
Integrated Pumping SystemAssistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:



Group Art Unit: 1763

Examiner: R. Bueker

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CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on <u>26 March 02</u> with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.	
<u>26 March 02</u> Date	<u>William Bueker</u> Signature

RESPONSE TO RESTRICTION REQUIREMENT DATED FEBRUARY 26, 2002

In response to the Restriction Requirement dated February 26, 2002, having a shortened statutory period for response set to expire on March 26, 2002, Applicants elect claims 11-20 and 25-26, Group II, and request reconsideration of the restriction requirement.

Although Applicants believe that no fee is due in conjunction with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/2981.P1/IBSS/CPS/WBP, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

IN THE CLAIMS:

Please withdraw claims 1-8, 21-24, 28, 30-38, and 40-41 for being drawn to a non-elected invention.

- (Withdrawn) An apparatus for processing a substrate, comprising:
a plurality of vacuum chambers, the vacuum chambers defining a peripheral envelope of space;